

INFORMATION DISCLOSURE
CITATION IN AN
APPLICATION



(PTO-1449)

ATTY DOCKET NO
49959-220

SERIAL NO
09/986.137

APPLICANT
Gilad ALMOGY, et al.


FILING DATE
November 07, 2001

GROUP
3662

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EXAMINER'S INITIALS	CITE NO	Document Number Number and Code	Publication Date MM-DD-YYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear
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[illegible]

3a. Author name of the author in CAPITAL LETTERS; title of the article (when appropriate); title of the journal, book, magazine, newspaper, etc.; volume, issue, and page numbers; date; publisher; address of publisher; city, state, and zip code; and country of publication.

Part 4: International Search Report dated 5/4/03

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DATE CONSIDERED

11-6-03

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
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EXAMINER'S INITIALS	CITE NO.	Include name of the author or CAPTION, DATE, and the title of the article, book, magazine, or other publication, including edition, page(s), volume, issue number(s), publisher, city and/or country where published.
		International Search Report dated August 4, 2003
		High throughput atomic force lithography with multiple aperture pixels; process improvement of atomic force lithography; Vac Sci Technol B 19 Nov Dec 1994
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